

RIE – Operating instruction

FAB STAFF ONLY:

1. Turn on the roughing pump- check nitrogen pressure before.
2. Turn on the chiller
3. Open the following valves: air pressure, nitrogen and water supply.
4. Turn on load lock pump.
5. Turn on main switch.
6. Press: Machine power, primary mech pump, lock pump.
7. Turn on the computer

ALL USERS:

8. Choose working cell- Utilities->select active chamber.
9. If you are working on the right chamber, turn on TMP (Utilities ->TMP On)
10. Press stand-by mode
11. Press service-> maintenance-> pump-> system.
12. Press service-> maintenance-> vent-> loadlock.
13. Load sample.
14. Press service-> maintenance-> pump-> system.
15. Press process->batch->file->load->....(batch name)
16. Press ready.
17. Only if both chambers are pumped proceed
18. Press run.
 - *insure the process is running without any warning, before loading your sample.
 - * While pumping the load lock press down the chamber door (For 1 sec).
19. After a process ends, unload your sample, and pump lock.

Loading sample procedure

1. Using capton tape, secure your sample to the Si wafer.
2. Gently put the Si wafer on top of the Graphite.
3. Do not touch anything in the working station.

RIE work protocol

- ❖ If you failed to hold down the lock door the system will not pump correctly and it might beep-> press silence -> repeat the action (and hold down the door)
- ❖ After the process will finish the system will beep for 10 sec, you can stop the beep by pressing Enter.
- ❖ If a wafer fall down in a cell or there is any alert, silence the alarm->press hold-> call for assistance. (Don't try fix the problem).
- ❖ Do not press abort!!!